



Field-Effect Transistor-Based Technology for Virus Detection

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Message from the Guest Editors

Dear Colleagues,

In recent years, diseases that spread rapidly worldwide such as the COVID-19 and Ebola viruses. Hence, new diagnostic tests and devices for virus detection that enable efficient testing with a faster response, higher sensitivity and selectivity, simpler sample processing. Among different biosensors, field-effect transistor (FET) biosensors could serve as one of the most promising candidates given their advantages of a miniaturized device size, simple fabrication method, and reliable sensing performance, etc.

Accordingly, this Special Issue seeks to showcase research papers and review articles that focus on but are not limited to FET-based biosensors for virus detection, including (1) new materials that can be used to fabricate new FET biosensors for virus detection; (2) novel designs, fabrication, control, and modeling of soft micro/nanodevices for virus detection; (3) advanced technologies for device fabrication; (4) development of new sensing components such as aptamers, nanobodies, molecular imprinted polymers (MIPs), etc.; (5) simulation and optimization of FET biosensors.





Editor-in-Chief

Message from the Editor-in-Chief

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